



Femtosecond Light Sources and Their Applications in the Deep UV, Vacuum UV, and Extreme UV

Guest Editor:

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Message from the Guest Editor

Dear Colleagues,

This Special Issue, “Femtosecond Light Sources and Their Applications in the Deep UV, Vacuum UV, and Extreme UV” calls for research articles on recent advances in the field of femtosecond light sources in DUV, VUV, and EUV and their applications. The topics include, but are not limited to, recent development on: frequency conversion, light amplification, pulse compression in nonlinear media, lasing and amplification in laser crystals, pulse shaping, seeded and SASE FELs for femtosecond pulses, with unprecedented parameters. The topics also cover ultrafast and nonlinear spectroscopies with advanced femtosecond coherent sources and new findings from them.

Dr. Yuichiro Kida
Guest Editor





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Message from the Editor-in-Chief

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